

P-615 NanoCube® XYZ Piezo System

Long-Travel Multi-Axis Piezo Stage for Precision Alignment Applications



P-615 NanoCube® XYZ Nanopositioning System provides up to 420 x 420 x 300 µm travel range

- Up to 420 x 420 x 300 µm Travel Range
- Resolution 1 nm
- Parallel-Kinematics / Metrology for Enhanced Responsiveness / Multi-Axis Precision
- Clear Aperture of 10 mm Ø, Ideal for Alignment and Photonics Packaging Applications
- Outstanding Lifetime Due to PICMA® Piezo Actuators
- Open- & Closed-Loop Versions
- Vacuum-Compatible Versions to 10⁻⁹ hPa
- Frictionless, High-Precision Flexure Guiding System

The P-615 NanoCube® is a multi-axis piezo nanopositioning and alignment system. Its 420 x 420 x 300 µm, XYZ positioning and scanning range comes in a compact package. Equipped with a zero-stiction, zero-friction guidance system, this NanoCube® provides motion with ultra-high resolution and settling times of only a few milliseconds.

Fiber Positioning

The P-615 NanoCube® is equipped with a fiber adapter inter-

face similar to the P-611.3SF and accommodates all F-603-series fiber holders and accessories. Fiber optics handling is facilitated by the clear aperture.

Double Stiffness for Fast Response

The P-615's unique flexure design has double the stiffness in the vertical axis than in X and Y, providing faster response and higher operating frequencies under load. For example, the settling time to reach a commanded position with 1% accuracy is only 15 ms in the Z-axis with 100 g load (as opposed to 10 ms without load).

Open-Loop and Closed-Loop Operation

The open-loop basic model P-615.30L is ideal for applica-

tions where fast response and very high resolution are essential but specifying or reporting absolute position values is either not required or is handled by external sensors, e.g. in tracking or fiber positioning tasks. In open-loop mode, the piezo displacement is roughly proportional to the applied voltage (see p. 2-184).

Capacitive Sensors for Highest Accuracy

The P-615.3C models are equipped with high-accuracy, capacitive position sensors. PI's proprietary capacitive sensors measure position directly and without physical contact. They are free of friction and hysteresis, a fact which, in combination with the positioning resolution of well under 1 nm, makes it possible to achieve very high levels of linearity. A further advantage of direct metrology with capacitive sensors is the high phase fidelity and the high bandwidth of up to 10 kHz.

Active and Passive Guidance for Nanometer Flatness and Straightness

Wire-cut flexures optimized with Finite Element Analysis (FEA) are used to guide the stage. The FEA techniques give the design the highest possible stiffness and minimize linear and angular runout. Further enhancement is achieved by active trajectory control: multi-axis nanopositioning systems equipped with parallel metrology are able to measure platform position in all degrees of freedom against a common, fixed reference. In such systems, undesirable motion from one actuator in the direction of another (cross-talk) is detected immediately and actively compensated by the servo-loops. This can keep deviation from a

Ordering Information

P-615.3CD

NanoCube® XYZ Nanopositioning System with Long Travel Range, 350 x 350 x 250 µm, Parallel Metrology, Capacitive Sensors, Sub-D Connector

P-615.3CL

NanoCube® XYZ Nanopositioning System with Long Travel Range, 350 x 350 x 250 µm, Parallel Metrology, Capacitive Sensors, LEMO Connector

P-615.30L

NanoCube® XYZ Nanopositioning System with Long Travel Range, 420 x 420 x 300 µm, Parallel Metrology, Open-Loop, LEMO Connector

P-615.3UD

NanoCube® XYZ Nanopositioning System with Long Travel Range, 350 x 350 x 250 µm, Parallel Metrology, Capacitive Sensors, Sub-D Connector, Vacuum Compatible to 10⁻⁹ hPa

trajectory to under a few nanometers, even in dynamic operation.

Ceramic Insulated Piezo Actuators Provide Long Lifetime

Highest possible reliability is assured by the use of award-winning PICMA® multilayer piezo actuators. PICMA® actuators are the only actuators on the market with ceramic-only insulation, which makes them resistant to ambient humidity and leakage-current failures. They are thus far superior to conventional actuators in reliability and lifetime.

Application Examples

- Micromanipulation
- Biotechnology
- Semiconductor testing
- Photonics / integrated optics

P-611.3 NanoCube® XYZ Piezo Stage

Compact Multi-Axis Piezo System for Nanopositioning and Fiber Alignment



NanoCube® XYZ-nanopositioning system,
100 x 100 x 100 µm closed-loop travel range, resolution 1 nm

- Up to 120 x 120 x 120 µm Travel Range
- Very Compact: 44 x 44 x 44 mm
- Resolution to 0.2 nm, Rapid Response
- Frictionless, High-Precision Flexure Guiding System
- Outstanding Lifetime Due to PICMA® Piezo Actuators
- Fast Multi-Axis Scanning
- Version with Integrated Fiber Adapter Interface
- Cost-Effective Mechanics/Electronics System Configurations

The P-611 NanoCube® piezo stage is a versatile, multi-axis piezo-nanopositioning system. Its 100 x 100 x 100 µm positioning and scanning range comes in an extremely compact package of only 44 x 44 x 44 mm. Equipped with a stiff, zero-stiction, zero-friction guiding system, this NanoCube® provides motion with ultra-high resolution and settling times of only a few milliseconds. The minimal moved masses and the stiff

piezo drive make it ideal for high-throughput applications such as fiber alignment where it enables significantly faster device characterization than achievable with conventional motorized drives.

Closed-Loop and Open-Loop Versions

High-resolution, fast-responding, strain gauge sensors (SGS) are applied to appropriate locations on the drive train and provide a high-bandwidth, nanometer-precision position feedback signal to the controller. The sensors are connected in a full-bridge configuration to eliminate thermal drift, and assure optimal position stability in the nanometer range.

The open-loop models are ideal for applications where fast response and very high resolution are essential, but absolute

positioning is not important, e.g. in tracking or fiber positioning. They can also be used when the position is controlled by an external linear position sensor such as an interferometer, a PSD (position sensitive diode), CCD chip / image processing system, or the eyes and hands of an operator.

Versatility & Combination with Motorized Stages

The P-611 family of piezo stages comprises a variety of single- and multi-axis versions (X, XY, Z, XZ and XYZ) that can be easily combined with a number of very compact manual or motorized micropositioning systems to form coarse/fine positioners with longer travel ranges (see p. 2-20, p. 2-36 and p. 2-50). For fiber positioning tasks, several fiber, waveguide and optics adapters are available for mounting on the NanoCube® P-611.3SF (e.g. for combination with the F-206.S nanoalignment system see p. 4-12).

High Reliability and Long Lifetime

The compact P-611 systems are equipped with preloaded

Ordering Information

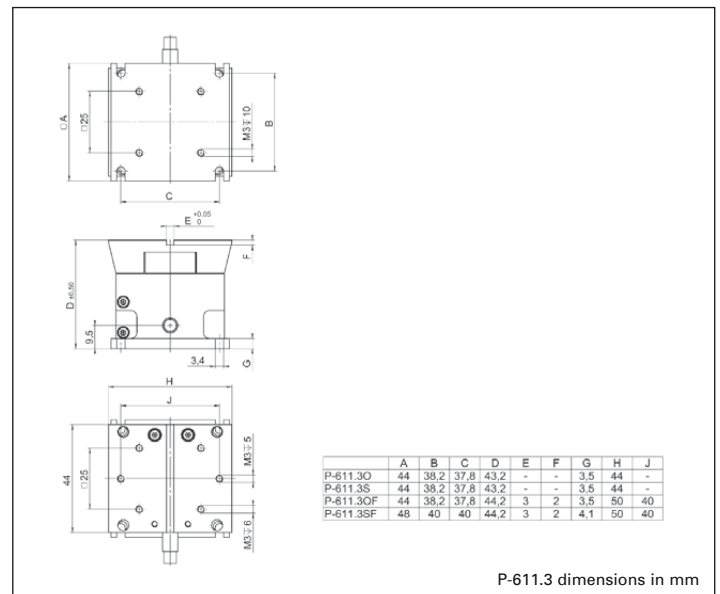
P-611.3S
NanoCube® XYZ Nanopositioning System, 100 x 100 x 100 µm, Strain Gauge Sensors

P-611.3O
NanoCube® XYZ Nanopositioning System, 100 x 100 x 100 µm, Open-Loop

P-611.3SF
NanoCube® XYZ Nanopositioning System, 100 x 100 x 100 µm, Strain Gauge Sensors, Fiber Adapter Interface

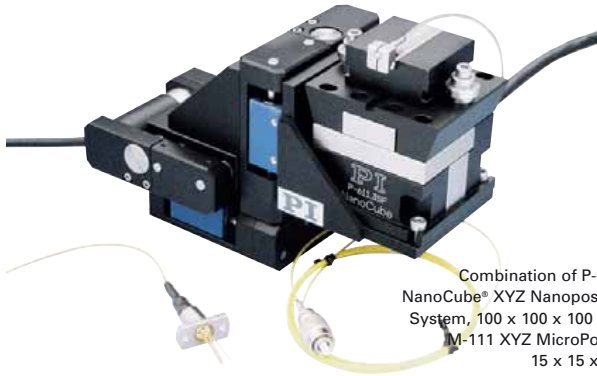
P-611.3OF
NanoCube® XYZ Nanopositioning System, 100 x 100 x 100 µm, Open-Loop, Fiber Adapter Interface

PICMA® high-performance piezo actuators which are integrated into a sophisticated, FEA-modeled, flexure guiding system. The PICMA® actuators feature cofired ceramic encapsulation and thus offer better performance and reliability than conventional piezo actuators. Actuators, guidance and sensors are maintenance-free and not subject to wear, and thus offer an extraordinary reliability.



Application Examples

- Photonics / integrated optics
- Micromanipulation
- Biotechnology
- Semiconductor testing
- Fiber positioning



Combination of P-611.3SF
NanoCube® XYZ Nanopositioning
System, 100 x 100 x 100 µm and
M-111 XYZ MicroPositioner
15 x 15 x 15 mm

Technical Data

Model	P-611.3S P-611.3SF	P-611.3O P-611.3OF	Units	Tolerance
Active axes	X, Y, Z	X, Y, Z		
Motion and positioning				
Integrated sensor	SGS			
Open-loop travel, -20 to +120 V	120 / axis	120 / axis	µm	min. (+20%/0%)
Closed-loop travel	100 / axis	–	µm	
Open-loop resolution	0.2	0.2	nm	typ.
Closed-loop resolution	1	–	nm	typ.
Linearity	0.1	–	%	typ.
Repeatability	<10	–	nm	typ.
Pitch in X,Y	±5	±5	µrad	typ.
Runout θ_x (Z motion)	±10	±10	µrad	typ.
Yaw in X	±20	±20	µrad	typ.
Yaw in Y	±10	±10	µrad	typ.
Runout θ_y (Z motion)	±10	±10	µrad	typ.
Mechanical properties				
Stiffness	0.3	0.3	N/µm	±20%
Unloaded resonant frequency X / Y / Z	350 / 220 / 250	350 / 220 / 250	Hz	±20%
Resonant frequency @ 30 g X / Y / Z	270 / 185 / 230	270 / 185 / 230	Hz	±20%
Resonant frequency @ 100 g X / Y / Z	180 / 135 / 200	180 / 135 / 200	Hz	±20%
Push/pull force capacity in motion direction	+15 / -10	+15 / -10	N	Max.
Load capacity	15	15	N	Max.
Drive properties				
ceramic type	PICMA® P-885	PICMA® P-885		
Electrical capacitance	1.5	1.5	µF	±20%
Dynamic operating current coefficient	1.9	1.9	µA/(Hz • µm)	±20%
Miscellaneous				
Operating temperature range	-20 to 80	-20 to 80	°C	
Material	Aluminum, steel	Aluminum, steel		
Dimensions	44 x 44 x 43.2 SF-version: 44 x 50 x 44.2	44 x 44 x 43.2 OF-version: 44 x 50 x 44.2	mm	
Mass	0.32	0.32	kg	±5%
Cable length	1.5	1.5	m	±10 mm
Sensor connector	Sub-D	–		
Voltage connection	Sub-D	Sub-D		
Recommended controller / amplifier	E-664 Nanocube® Controller (p. 2-137)	3 x E-610.00F OEM amplifier modules (p. 2-110); E-663 3-channel amplifier, bench-top (p. 2-136)		

Resolution of PI Piezo Nanopositioners is not limited by friction or stiction. Value given is noise equivalent motion with E-503 amplifier (p. 2-146)
Dynamic Operating Current Coefficient in µA per Hz and µm. Example: Sinusoidal scan of 50 µm at 10 Hz requires approximately 0.8 mA drive current.
Adapter cable with LEMO connectors for sensor and operating voltage available.